

## **IN THE SPECIFICATION:**

Page 10, please further amend the paragraph beginning on line 10 to read:

— — Fig. 2 shows a schematic setup of a coating system 21 with online closed loop correction. This system comprises a coating source 23 at a coating location on a circular path on which substrates 31 cyclically move in a direction of movement, controlled by the coating source supply 25 which typically regulates coating parameters such as power, gas flow, magnet motion etc. This coating source 25 itself is regulated by an additional controller 27 which receives signals from a thickness detection system 33. This thickness detection system can be realized by measuring the actual optical transmission and/or reflection characteristic of the substrate 31 on the holder 29, at more than one position on the substrates and at a sensing location that is spaced from the coating location in the direction of movement of the substrates along the path. A multiple detector system is required for measuring the uniformity at least approximately perpendicular to the direction of motion of the substrates on their hold (curved arrow). — —